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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Pan et al.

Serial No.: 09/614,113

Filed: July 12, 2000

For: TECHNIQUE FOR ELIMINATION OF
PITTING ON SILICON SUBSTRATE
DURING GATE STACK ETCH

Examiner: C. Brown

Group Art Unit: 1765

Attorney Docket No.: 2915.3US (96-
0149.2)

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REMARKS UNDER 37 C.F.R. §1.116

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Sir:

The following amendments and remarks are filed in response to the Examiner's remarks in the Final Office Action mailed February 22, 2002, the three-month shortened statutory period for response to which expires on May 22, 2002.

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